

31.03.2022

Soft Lithography

1990's : Primarily to circumvent the problems of Photo - Lithography.

Stephen Chou → Princeton → Nano Imprint Lithography - ✓

George Whitesides → Harvard → REM. - ✓

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Soft Lithography Methods

- These are rather specific towards soft surfaces (polymers and gels) as well as for applications which do not require extremely stringent quality control or defect free patterns like micro electronics.
- There are several application areas, where large area meso and nano scale structures are necessary, but even if there are some defects here and there, it is fine.
- Sensors, Biological applications, structural color, textured hydrophobicity: progress in all these areas depend on availability of robust, simple, easy to execute and CHEAP patterning techniques that can create large area ($\sim \text{cm}^2$) patterns with good reproducibility
- The ability to create defect free structures should be reasonable.

Photo lithography is every well defined technique.
Soft Litho : A Suit/ Collection of different techniques
All SL techniques are capable of patterning soft material including Polymer (PR is not reqd.).

Photo Lithography:

Aimed at the micro electronic industry. Defect tollerence is very very low.
Defect is NOT allowed. → aimed for perfection.

Soft Lithography:

Aimed at bulk - nano applications that require meso and nano scale patterns over large areas Like self cleaning surface. So even if there are some defects here and there, its accepted.

↳ Can work for wide variety of soft materials — Polymers, Gels, Sol-Gel derived inorganic materials etc.

Discussion on Classification of Polymers

Glassy Polymer (Thermo Plastic)

- Long chain entangled polymers. No physical cross links between the chains
- T_g (Glass Transition Temperature) is an important property. Above T_g there is a sudden drop in viscosity. The polymer starts behaving like a liquid.
- Such polymers can be softened in presence of a Solvent as well. The solvent molecules penetrate into the polymer matrix and results in reduction of effective T_g of the polymer.

Cross Linked Polymer (Thermo Set)

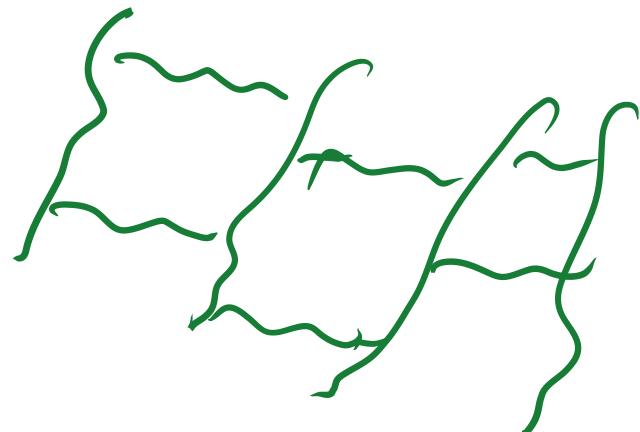
- The chains are physically crosslinked.
- Depending on the chain configuration these polymers can be flexible. (Rubbery)
- Heating will degrade the polymer (wont make it fluid like).
- In presence of solvent molecules can swell, but wont lose structural integrity.
- Many rubbery, cross linked polymers have sub zero T_g .

Long Chain
Non Cross linked
 melts /
 softens above
 T_g
 η drops

→ Cross linked
 polymers .
 → Elastic like

Cross Linked Polymers (or Thermo Set)

DO NOT Flow
above T_g



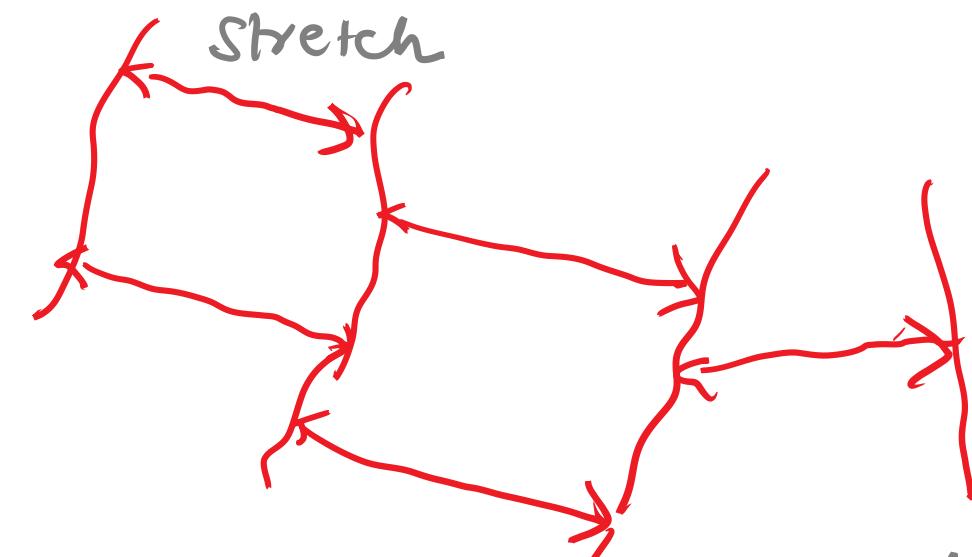
→ Chains are cross linked

→ Stretch (apply force from outside)

→ The energy supplied for stretching → remains stored as elastic deformation energy within the chains

→ They do not disintegrate.

→ When the external force is withdrawn, this energy is released & object takes back its original shape.



Glassy Polymers →

1st April 2022

There is no crosslink.

But there are long chain molecules →

there is entanglement → So at Room Temp.
the individual molecules cannot move / change
position w.r.t each other → behave as
solids -

→ As you heat up → The translational K.E of
the molecules ($k_B T$) increases → So the chains
can overcome cohesive interaction and entanglement
→ starts to move / can change
position w.r.t each other / liquid like.

Above a critical Temp \rightarrow The material starts behaving like a liquid \rightarrow

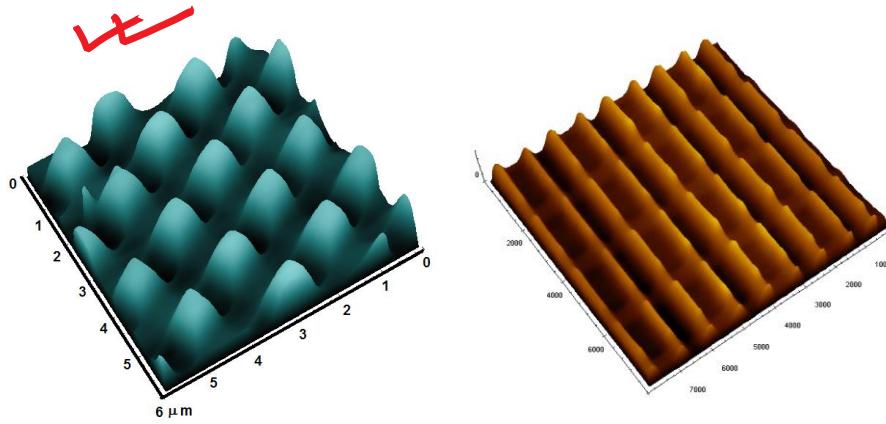
- \rightarrow Chains / molecules change position w.r.t to each other
- \rightarrow Viscosity drops. (n)

Temp at which $n \downarrow$, Glass Transition Temp.

Soft Lithography Techniques: Classifications

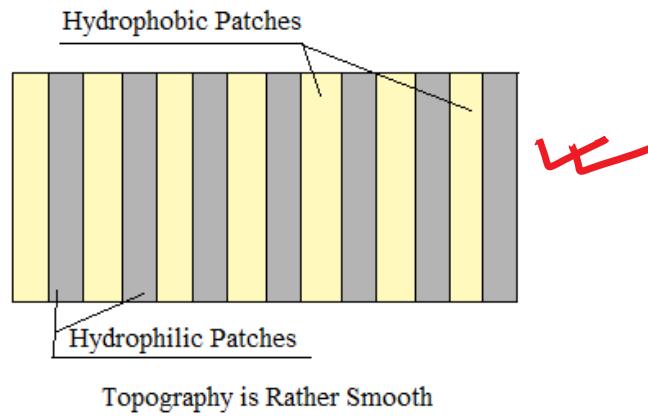
Based on the Nature of Patterns:

- Chemical Patterns
- Topographic Patterns



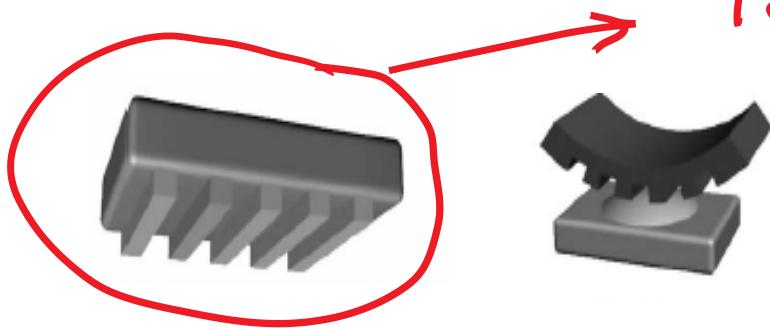
Based on the Nature of Stamp Used:

- Flexible Stamp
- Rigid Stamp



Printing Group of Techniques

Molding group of Techniques



*Topographically
Patterned Stamp.*

Eqv. to the mask in
Photo lithog
raphy

Master//
Stamp//
Mold

Soft Lithography Techniques: Classifications

Topographic Patterns:

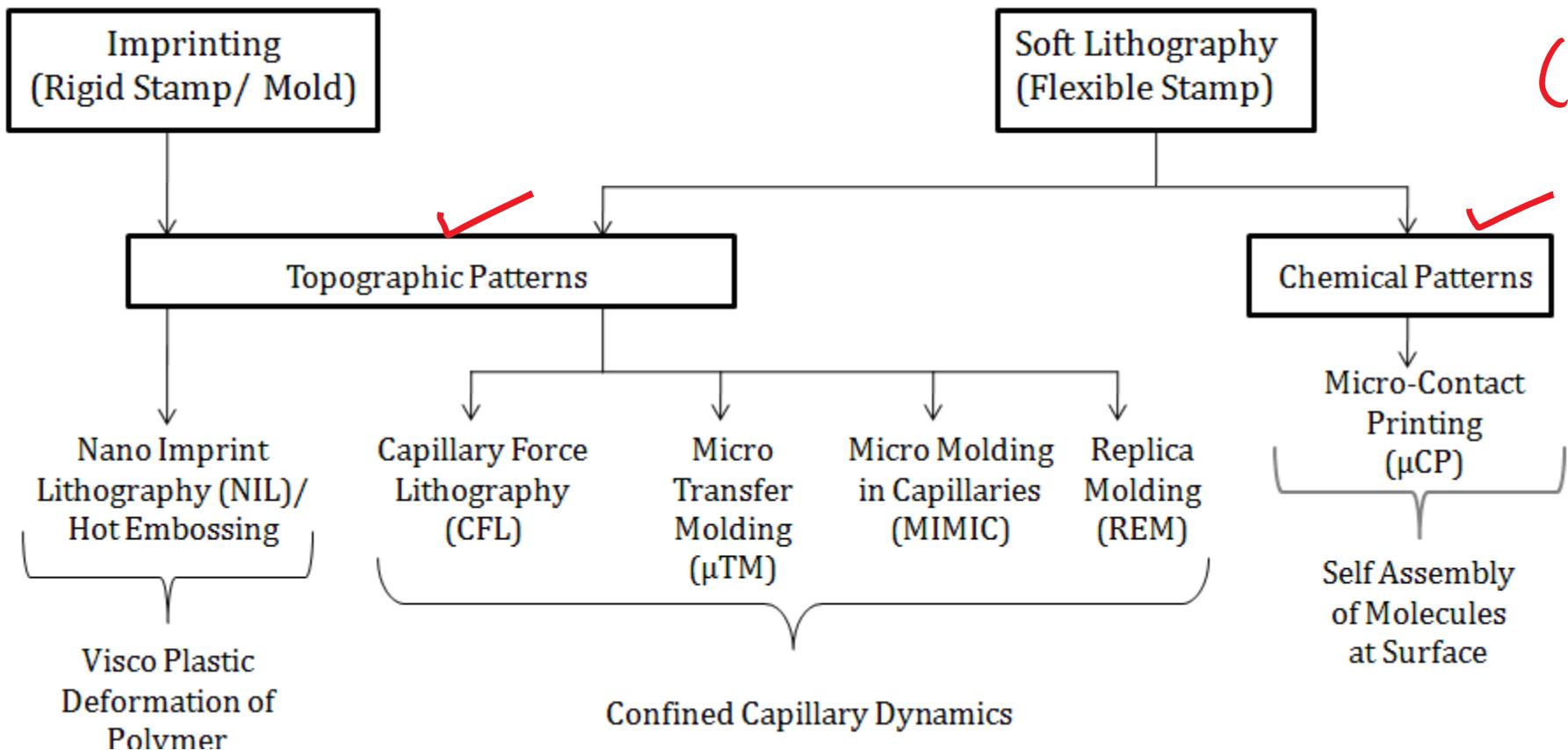
Nano Imprint Lithography (NIL): Visco Plastic Deformation of a Softened Polymer Layer under External Pressure

Chemical Patterns:

Are always based on some surface active molecules (Micro Contact Printing) (μ CP)

Micro Transfer Printing (μ TP): 3D structures

Classification

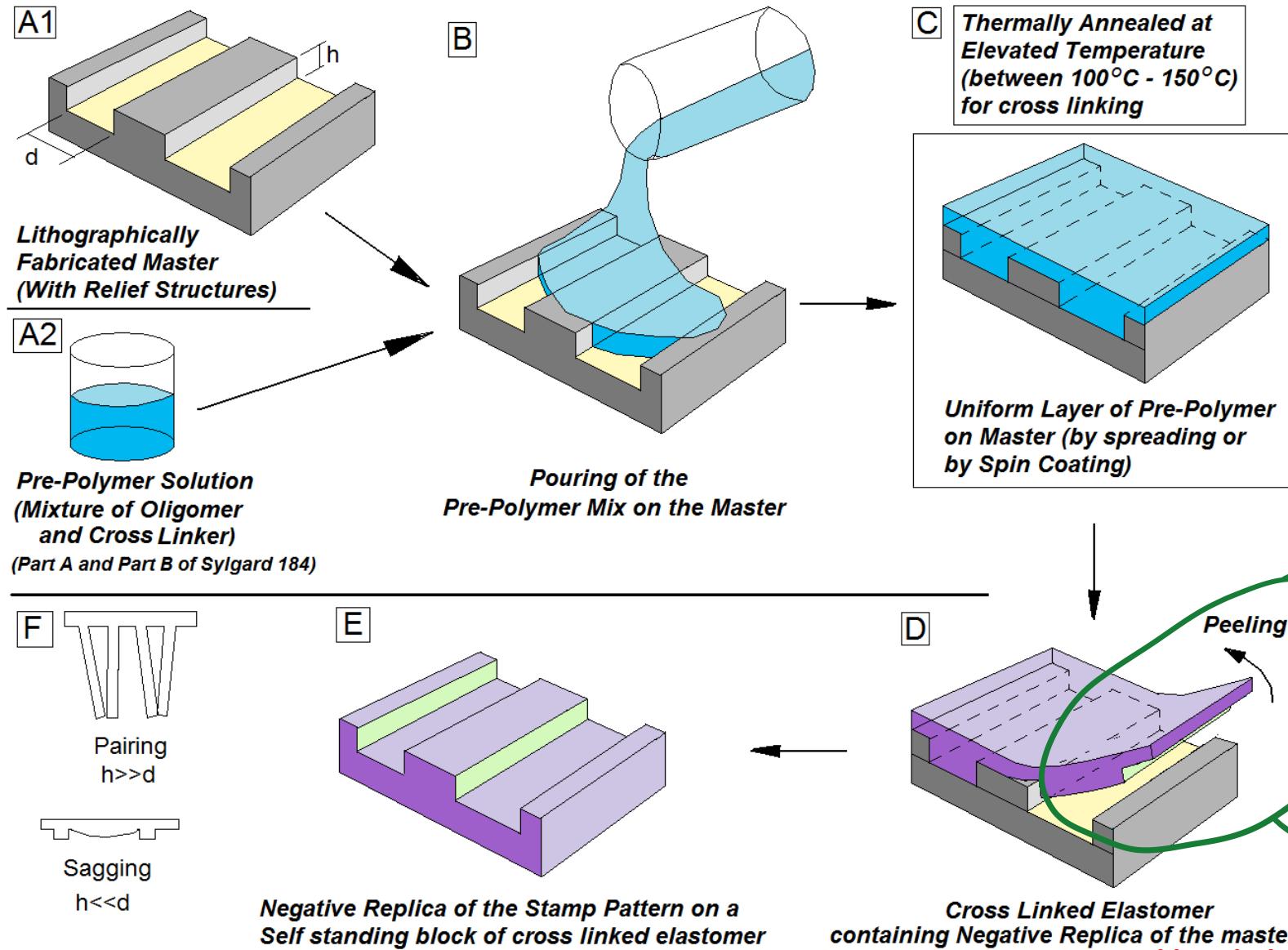


(1) Based on Type of Pattern

(2) Based on the type of the stamp.

→ Rigid
→ Flexible
stamp,

Replica Molding



Special Type of Material →

Thermo "Curable" Elastomer

Cross linked Poly Di Methyl Siloxane (PDMS)

PDMS at Room Temp is Liquid.

Its T_g is below Room Temp. Glossy Polymer is NOT flexible!! So can't Peel.



PDMS → Poly di methyl

Siloxane

(Silicone)

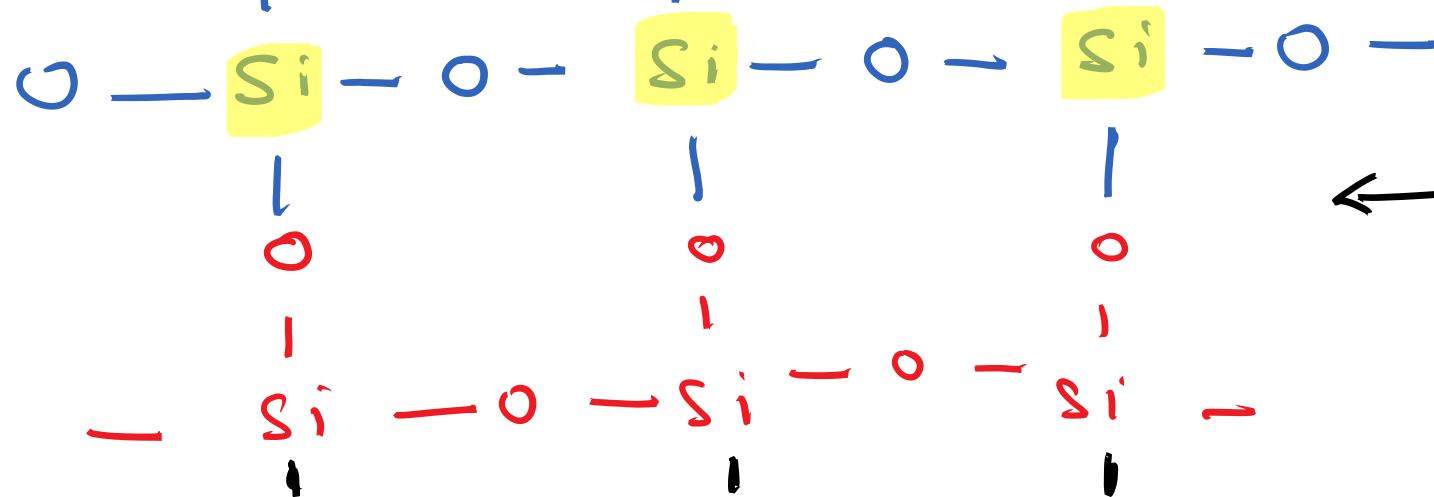
Inorganic Polymer

Since Si is present

at alternate location

Get more
flexibility.

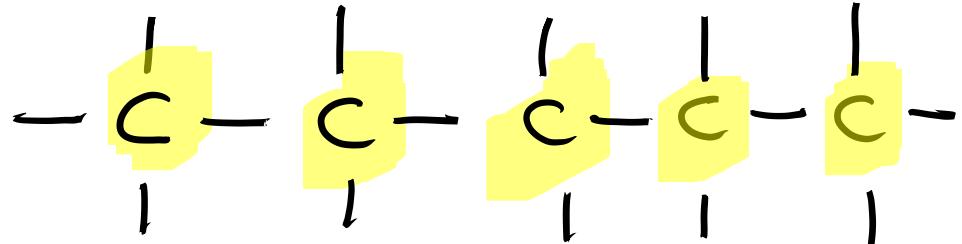
Thermo Curable



Polymer

(C-C back bone,

Organic
molecule)



As you heat up
the adjacent
polymer chains
join up -

(Cross linking
reaction happens
at elevated T up)

Soft / Flexible
Solid

Material for Replica Molding

- The material used for REM is Cross linkable Poly-dimethyl siloxane (PDMS), which falls into a general category of materials called elastomers.
- Elastomers are crosslinked amorphous polymers that are used at temperatures above their glass transition temperature, T_g .
- Above the glass transition temperature, molecules gain thermal energy that enables them to move in a coordinated manner, making the elastomers rubbery, soft and flexible.*

Commercial Product:

Sylgard 184

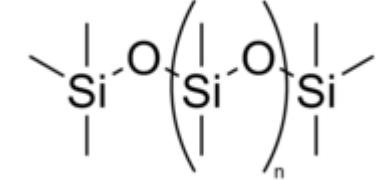
Shape: Shape of
the Container.

Sylgard Group of Products from Dow – Croning USA

A - Oligomer

B → Cross linker,
Catalyst

10:1



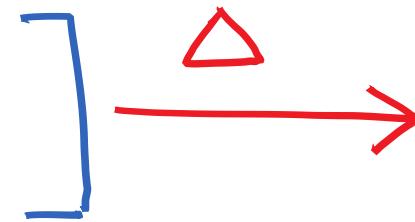
As you
thermally
anneal

A high viscous
Liquid

$\downarrow (\Delta)$ 120°C
6 hrs

Soft Elastic
Solid

A → Oligomer
B → Cross linker
(Catalyst)



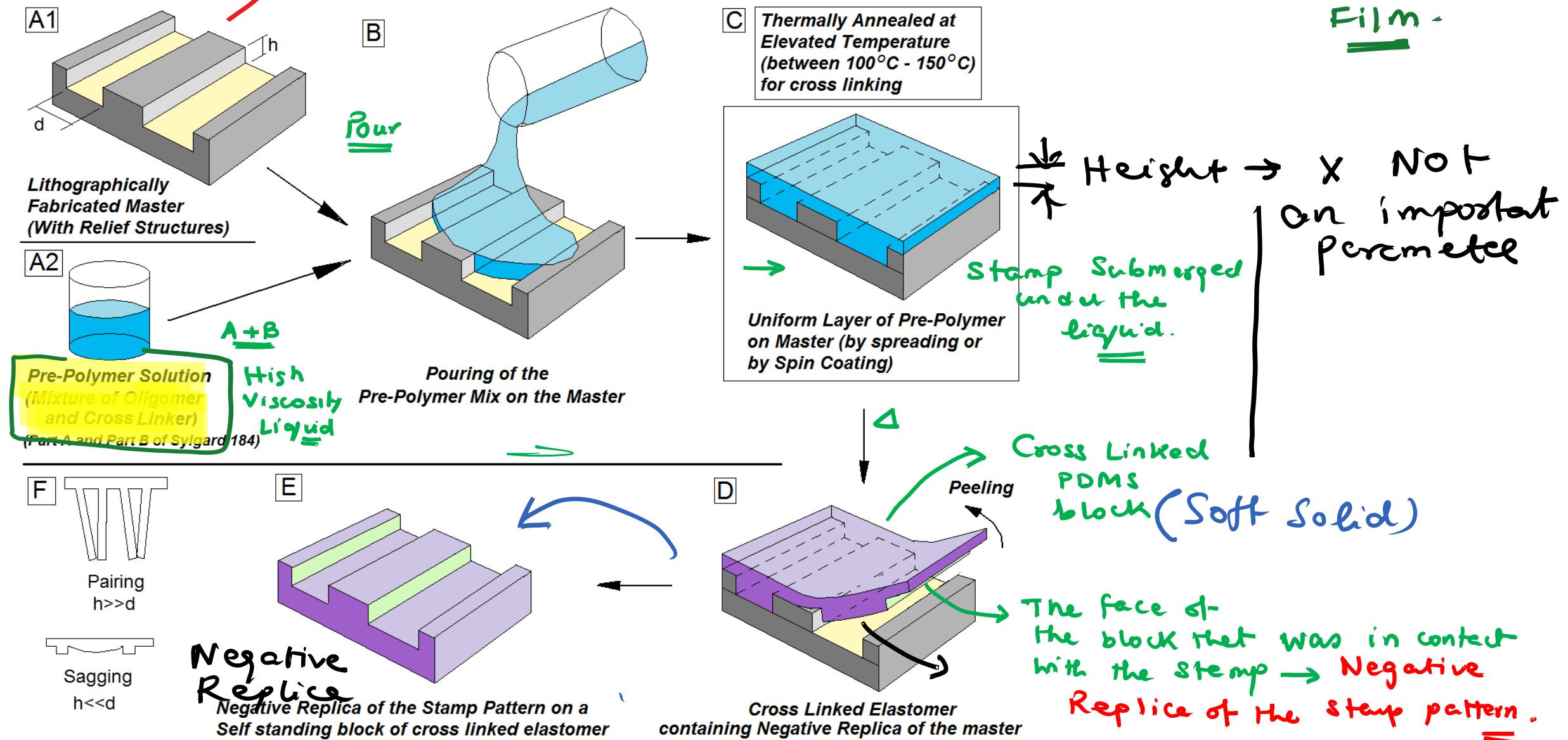
There is cross linking only
When you heat up.
X

If you mix A and B → Just keep it at room temperature → Then also there is cross linking → rate of cross linking is low (process is slow)

Thermal Annealing only expedites the cross-linking process.

Replica Molding

To topographically patterned stamp → Patterned film -

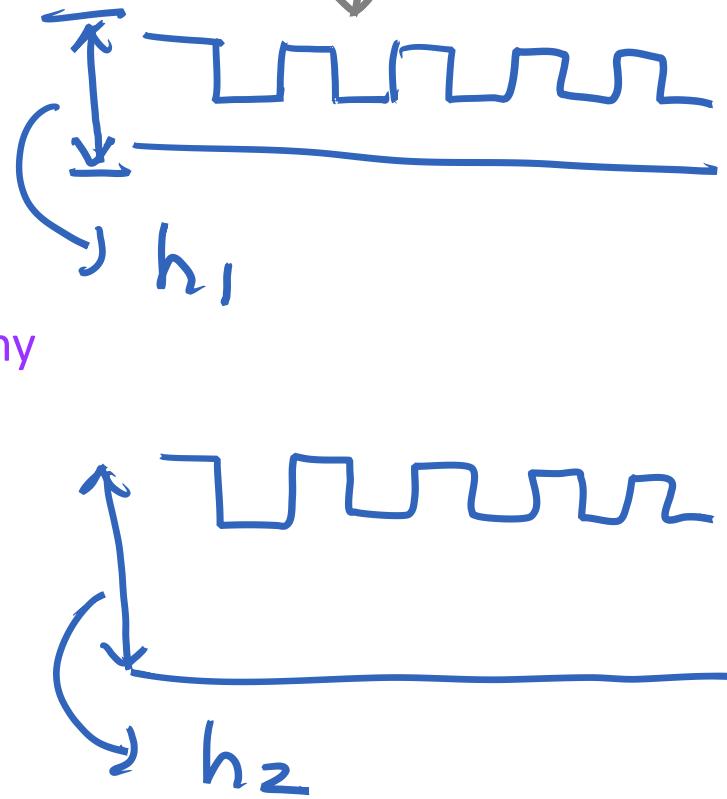


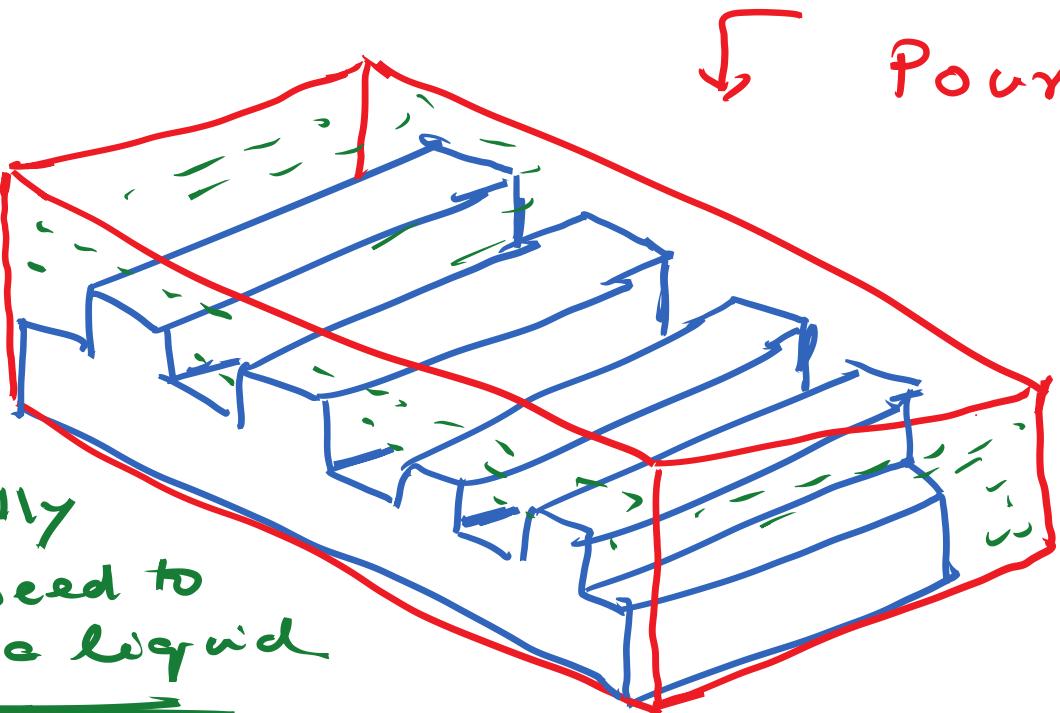
Cross Linked PDMS

- PDMS consists of an inorganic siloxane backbone and organic methyl groups attached to it.
- It is a flexible elastomer that can be used in a wide temperature range, it is optically transparent, biocompatible, inert and non-toxic and resistant to many chemicals.
- It is non-flammable and gas-permeable.
- Thermally and electrically it is insulating.
- The low surface energy of PDMS allows its release easily from templates and structures.
- Curing of PDMS can be done in room temperature, or rapid heat curing in temperatures of 60 – 120°C

So is block Thk important

The pattern morphology is independent of the thickness of the block.





Initially
you need to
have a liquid

↓ Pour Liquid → liquid will drain out

How small you can get
→ Simply depends on
the feature dimension
on the stamp.

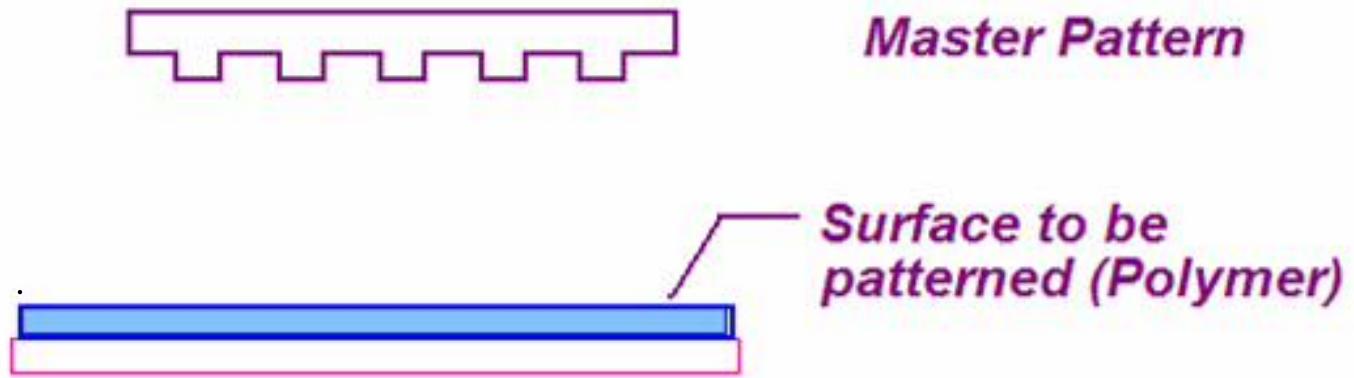
Does it work for
a Glossy Polymer?

Thermo Plastic??

- Replace Molding (REM)
- Soft Lithography Technique
- Secondary Patterning Technique

By replica Molding → we get a self standing block of cross linked PDMS.

NANO IMPRINT LITHOGRAPHY



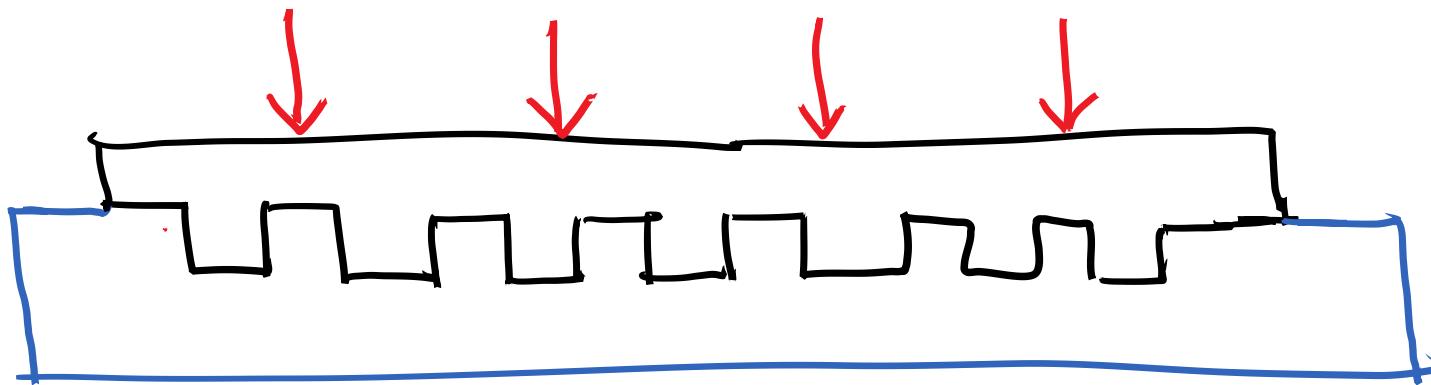
(1) Thin Film of
a **glossy Polymer**
(Spin Coating)

(2) RIGID Stamp .

1. Heat up the film above T_g
2. Press the Stamp against Softened film with Excess External pressure



Major Operational Problem (NIL)



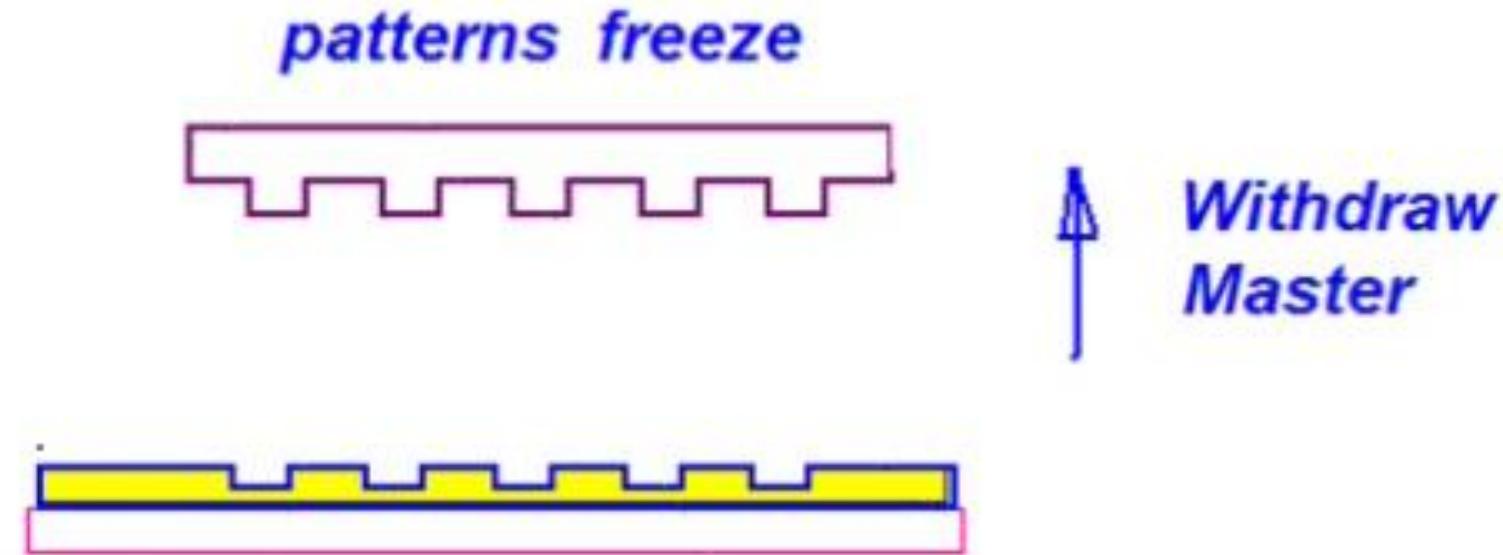
① NIL \rightarrow Can't be implemented without heating.

② NIL as well as REM \rightarrow Both produce a Negative Replace.

③ Applying Pressure from outside

- Mould breakage due to high External pressure
- Repeated usage + mechanical wear & Tear

NANO IMPRINT LITHOGRAPHY



Major Problem: → Mould Release

Rigid Stamp → Peeling Does not work.

Coat the Surface of the mould with some low surface Energy Coating → Stamp Release Agent.

Nano Imprint Lithography (NIL)

J. Vac. Sci. Technol. B, 14, 4129, 1996

Advantage:

- Large area patterning capability
- Applicable for many different polymers.
- Resolution achieved ~ 10 nm.
- Possible to achieve patterns over fairly large area.

Some Critical Issues and Limitations

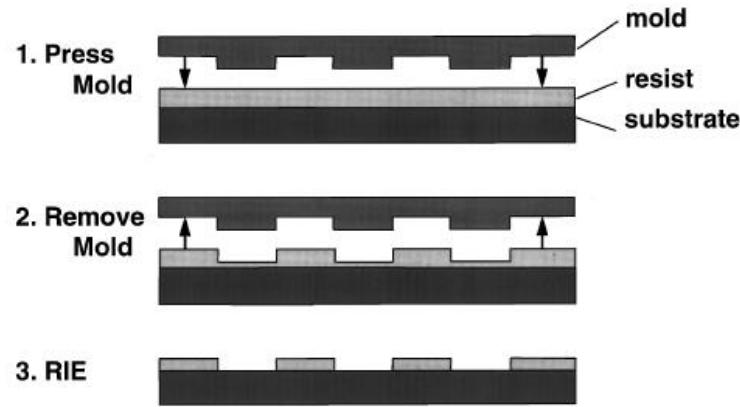
High Temperature

High Pressure

Adhesion of Mold with Resist (Polymer): Severe Chances of Mold Damage

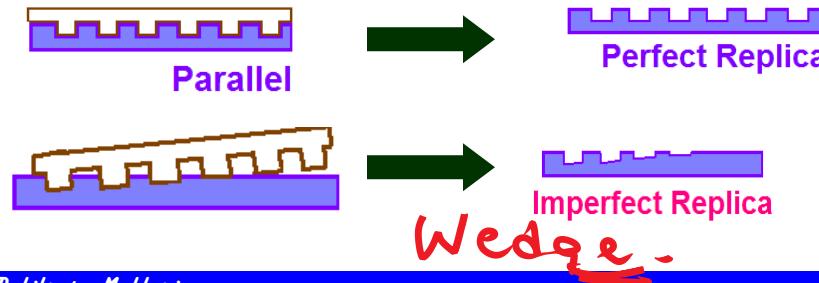
Critical Parallelism between mold and film has to be ensured!

Non Planar Surfaces cannot be patterned



One Limitation of all
Lithography Techniques
that we discussed so far

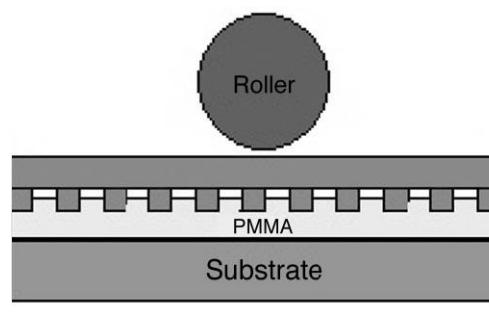
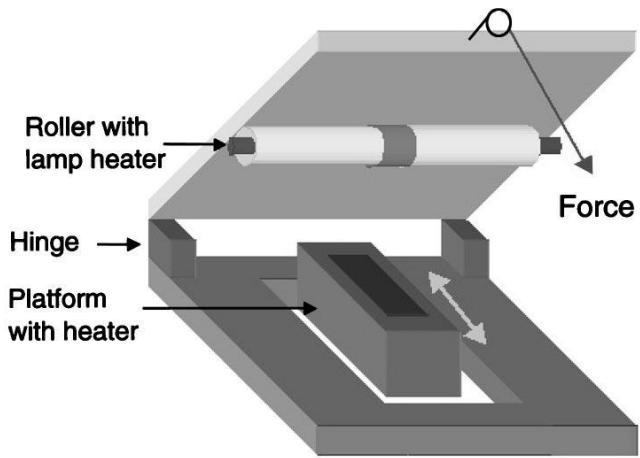
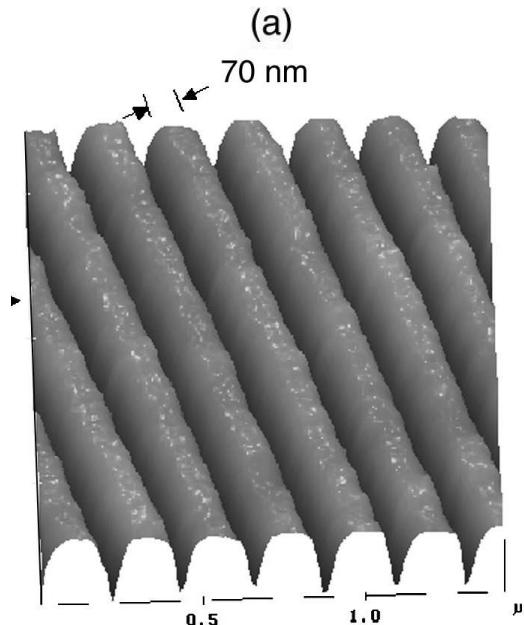
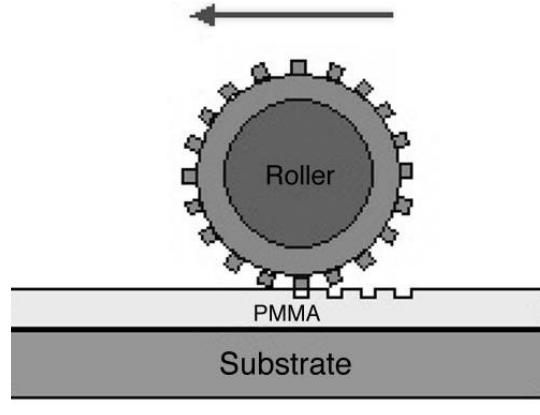
→ All are
Batch Process.



Mold Release agents

Roller Nano Imprint Lithography

All the configurations discussed so far, make the imprinting group of techniques batch type operation.



J. Vac. Sci. Technol. B, 16, 3926, 1998

Roll-to-Roll Nanoimprint Lithography

Continuous patterning

Possible.

* T&C apply

Film must
be on a
flexible base.

Surface of the
Roller drum is
patterened.

You don't
have the
temp to
ensure no
deformation

Nano-
patterned
substrate

Film will
try to
flatten

Rapid
cooling

Imprinting
roller

Possible to have polymer
films on a Flexible Base

Flexible
substrate

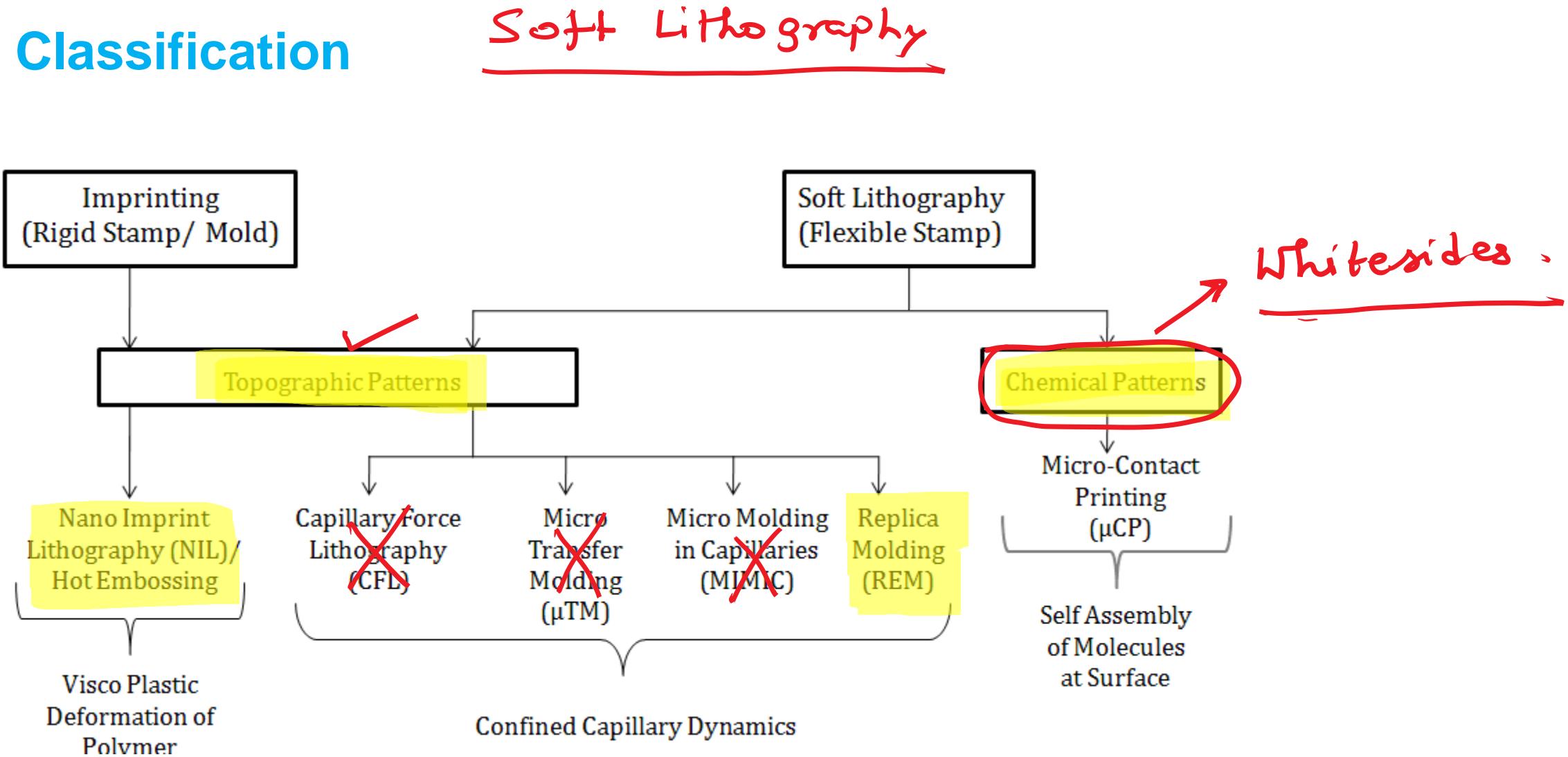
Locally Temp is high
viscosity is low ...

At this location the
film becomes soft →
So that it can deform

* Rate of heating
* Roller speed
* Film Draw up
Speed
* Rate of
Cooling -
→ Synchronized



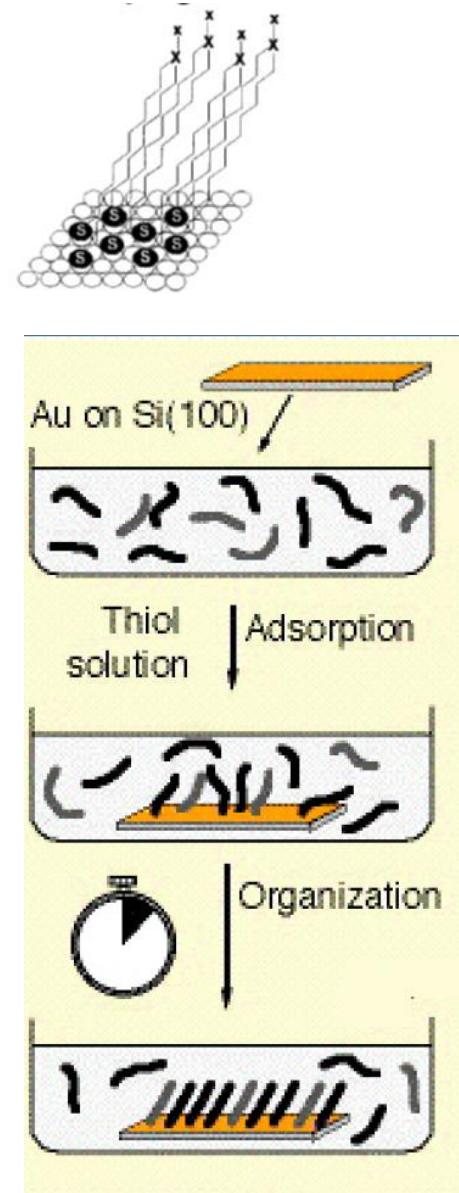
Classification



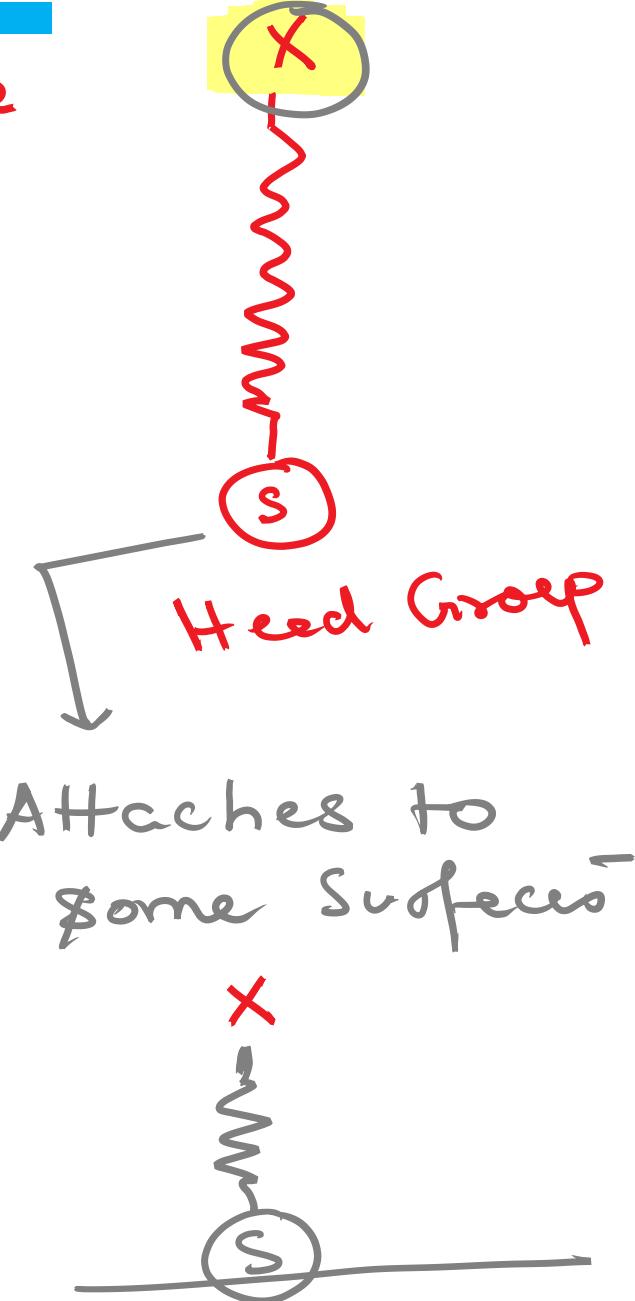
SAM (Self Assembled Monolayer)

- The presence of a ligand ($Y(CH_2)_nX$) which is reactive toward the surface ensures the attachment of the **silane** molecules with the substrate. The surface properties of the SAM surface (primarily if the SAM coated surface is hydrophobic or hydrophilic) depends on the nature of the head group, X. On the other hand, the binding of the SAM molecules to the surface is determined by the group Y.
- Some surfaces like gold or silver show excellent binding ability towards the silane molecules such as alkanethiolates.
- Alkylsiloxanes on hydroxyl-terminated surfaces such as Si/SiO₂, Al/Al₂O₃, glass etc. also exhibit good attachment properties.

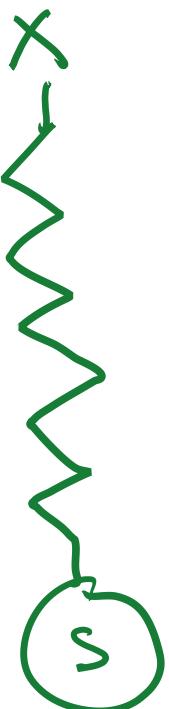
$X \rightarrow$ Can be hydrophilic / hydrophobic



Silane

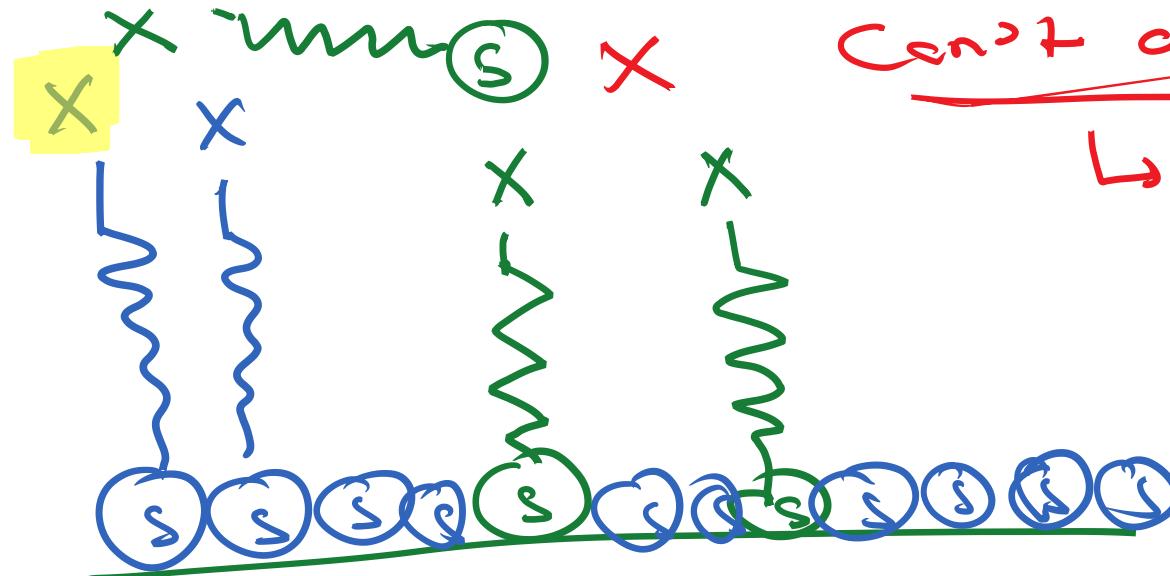


Attaches to
some surfaces



Self assembled monolayer (SAM)

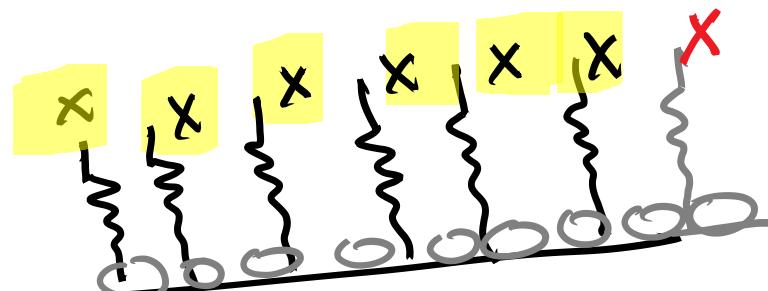
Effective wettability is governed by 'X'



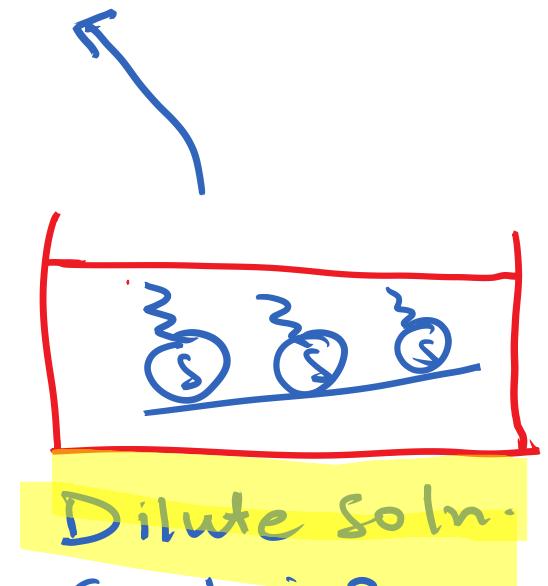
Can't attach here

↳ Can attach only to the surface.

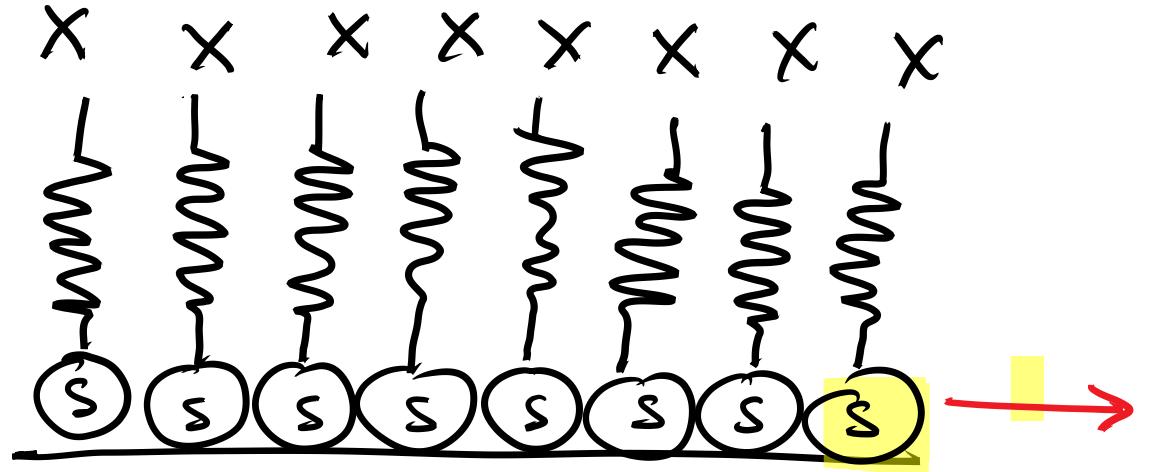
Surface is covered with a "monolayer" of these molecules.



SAM Covered Surface



Dilute soln. containing silene molecules.



SAM formation →
Method for modulating
Wettability.
→ What about chemical
patterns?

Once a Silene molecule
gets stuck (adsorbed)
on the surface → it does
not move.

② Maximum Coverage
→ complete monolayer.

③ Strategy for controlling the effective Wettability
of the surface.

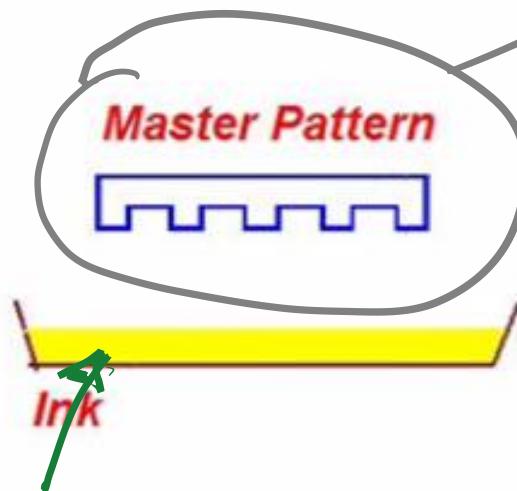
Can't be used for all

Surfaces → for surfaces to which
some silene attaches.
=

Micro Contact Printing (μ CP)

Sylgard Block created by
replica molding.

MICRO CONTACT PRINTING



Dilute Soln. of
Silene

Surface to be patterned
Polymeric or non polymeric

(Choose the Surface
in such a way that

it has affinity to
the Silene molecules.

Micro Contact Printing (μ CP)

MICRO CONTACT PRINTING

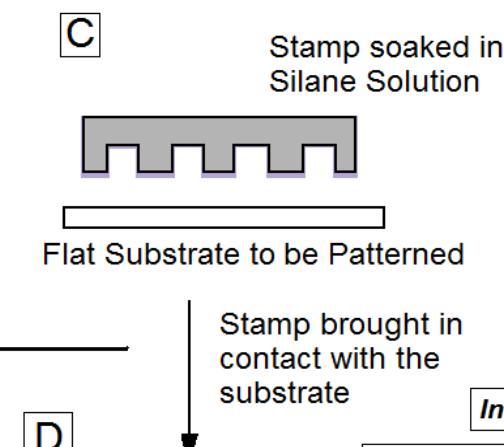
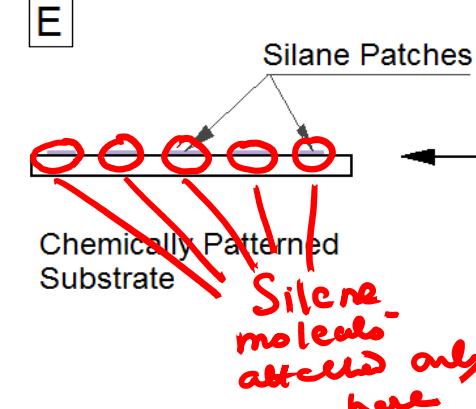
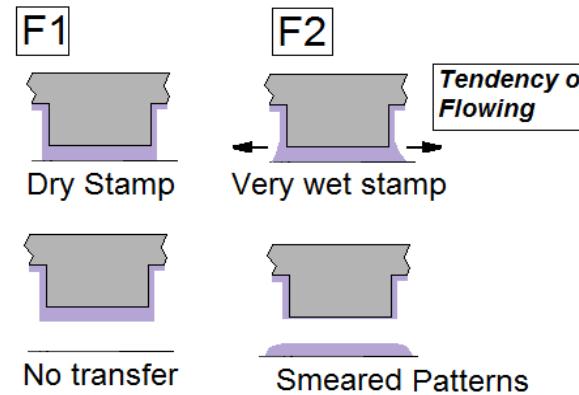
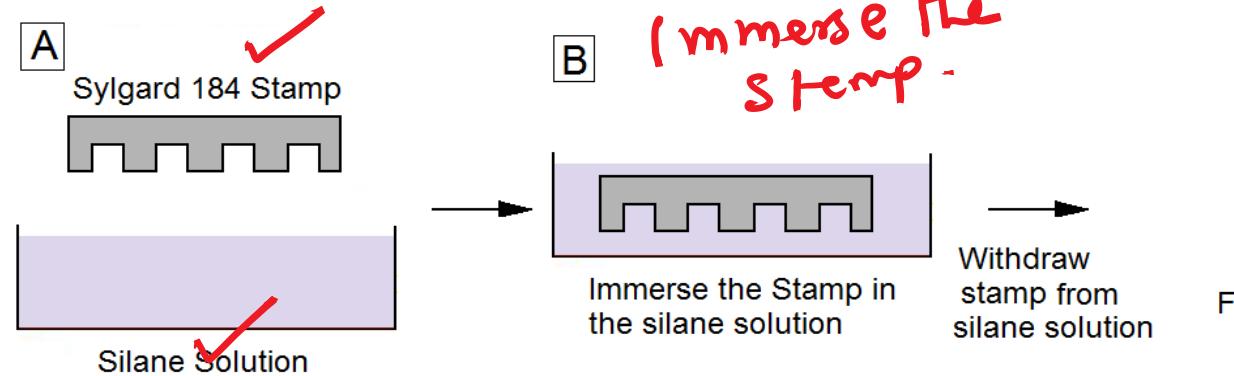
Master Pattern



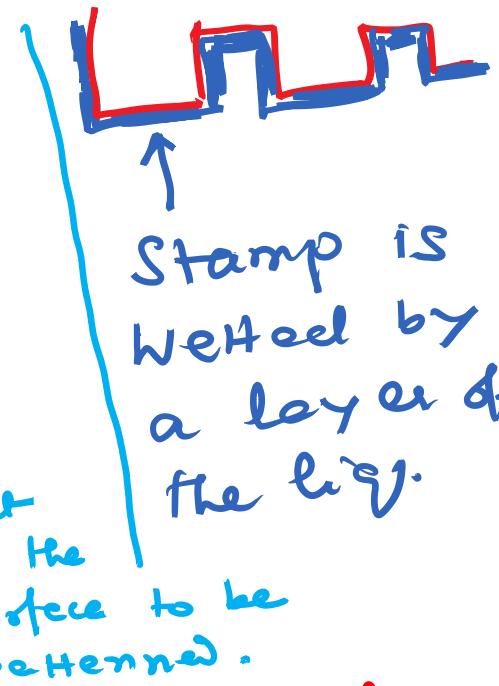
Ink

Surface to be patterned
Polymeric or non polymeric

Micro-contact Printing



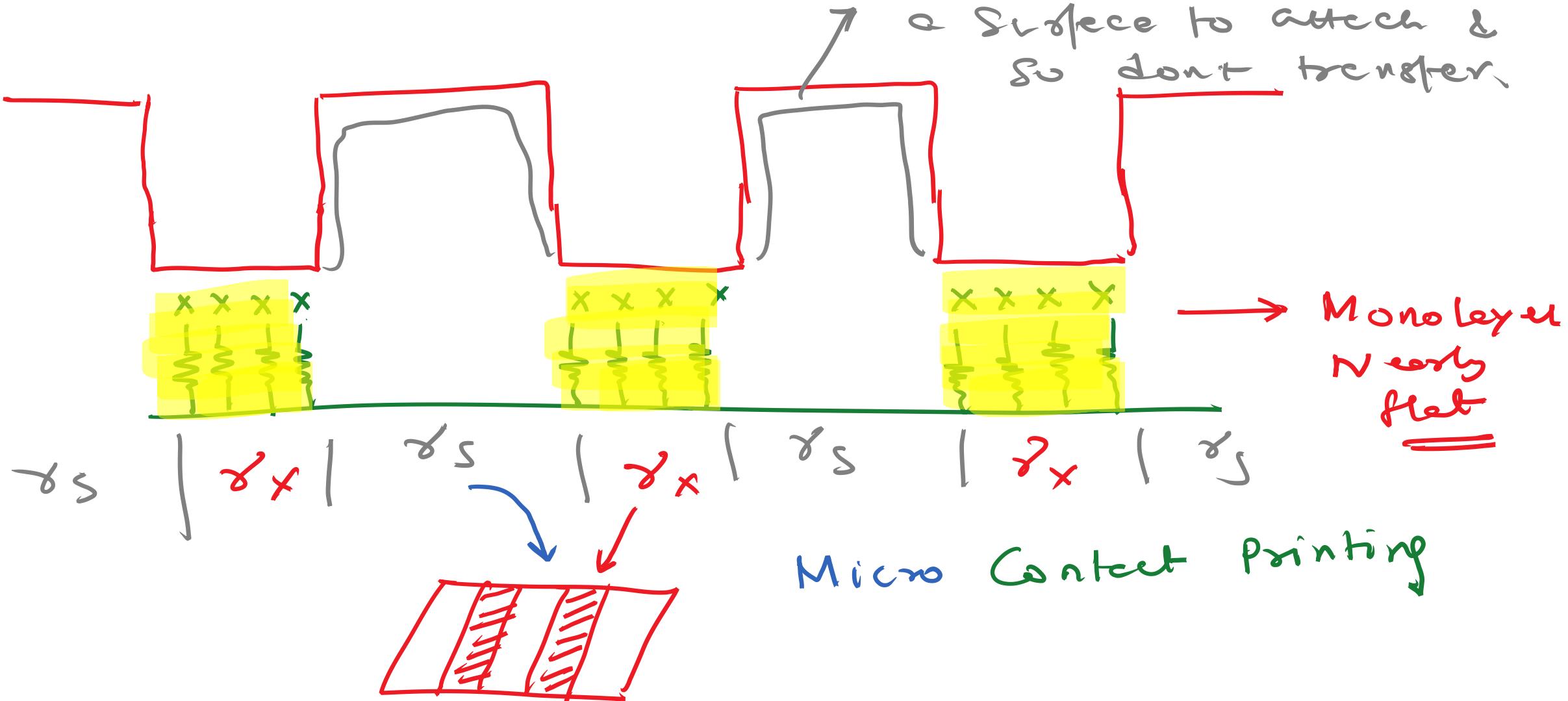
Stamp is Now wet.
But Silene molecule do not have preferential affinity to sylgard.



Bring the wet stamp in contact with the surface to be patterned.
Silene molecules of these areas find a surface to attach to

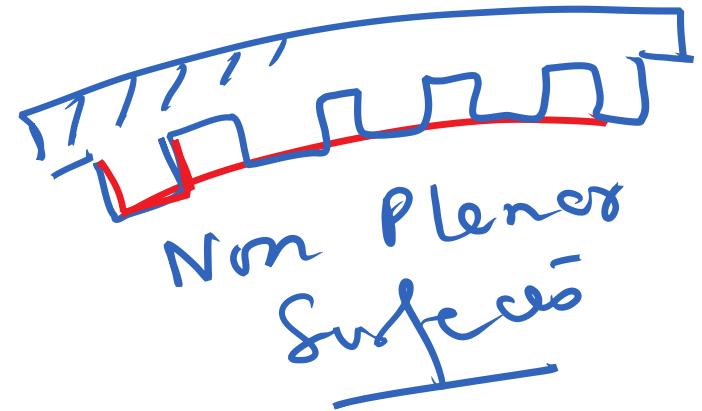
- Possible due to the ability of an elastomeric stamp to conform to a non-planar substrate with minimum distortion of the pattern on its surface.
- In this technique a patterned elastomeric stamp (typically PDMS) is inked with an alkanethiol and brought into contact with a gold surface.
- A self-assembled mono-layer of alkanethiolates forms at the stamp surface substrate interface.

Micro Contact Printing (μ CP)



Advantages of Soft Lithography

- Convenient, inexpensive, accessible to chemists, biologists, and material scientists
- Basis in self-assembly tends to minimize defects
- Many soft lithographic processes are additive and minimize waste of materials
- Readily adapted to rapid prototyping
- Isotropic mechanical deformation of PDMS mold or stamp provides routes to complex patterns
- No diffraction limit; features as small as 30 nm have been fabricated
- Nonplanar surfaces (lenses, optical fibers, and capillaries) can be used as substrates



Advantages of Soft Lithography

- Generation and replication of three-dimensional topographies or structures are possible
- Optical transparency of the mask allows through-mask registration and processing
- Good control over surface chemistry, very useful for interfacial engineering
- A broad range of materials can be used: functional polymers, sol - gel materials, colloidal materials, suspensions, solutions of salts, and precursors to carbon materials, glasses, and ceramics
- Applicable to manufacturing: production of indistinguishable copies at low cost
- Applicable in patterning large area

Soft Lithography: Limitations

- Patterns in the stamp or mold may distort due to the deformation (pairing, sagging, swelling, and shrinking) of the elastomer used
- Compatibility with current integrate-circuit processes and materials is not yet fully demonstrated
- Defect levels higher than for photolithography
- μ CP works well with only a limited range of surfaces; MIMIC is slow; REM, μ TM, and SAMIM leave a thin film of polymer over the surface.

Soft Lithography is a Secondary Patterning Technique, as it can **ONLY** produce a **NEGATIVE** replica of a given stamp or a master.